Annexe 1 : liste classée des publications

<u>Remarque sur l'ordre des auteurs</u> : pour toutes les publications issues de mon équipe et en l'absence de collaborations extérieures, j'utilise la règle générale suivante : contributeur majeur en 1er (en général le doctorant) suivi des autres contributeurs par ordre alphabétique.

1. Revues scientifiques avec comité de lecture

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4. ST Microelectronics, Central R&D, Crolles, France
5. UFRGS, Porto-Alegre, Brésil
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2. Centre for Microsystems Research, Lancaster University, Lancashire, UK
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5. Centro Nacional de Microelectronica, UAB, Bellaterra (Barcelona), Spain
6. Université de Twente, Pays-Bas
7. NXP Caen, France
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2. Conférences internationales avec actes et comité de lecture

<u>Critère retenu</u> : on trouvera dans cette rubrique les articles largement diffusés (disponible en ligne pour les plus récents) qui ont été sélectionnés par un comité de lecture et qui ont donné lieu à une présentation orale dans une conférence sélective (rang A).

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3. CNES, Centre Spatial de Toulouse

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2. ATEMI, service commun de l'Université Montpellier II

3. Centre d'Electronique et de Micro-optoélectronique de Montpellier (CEM2)

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[S19] «Conception de Microsystèmes Monolithiques Testables et Robustes aux Variations de Process», Ecole d'hiver Francophone sur les Technologies de Conception des systèmes embarqués Hétérogènes, Grand Hôtel de Paris, Villard-de-Lans, France – 10-12 janvier 2007.

[S20] «Design for Test of MNT-based Systems: Alternative Test Solutions for reduced Test Costs», MEMUNITY (The MEMS Test Community) workshop, Tuesday, March 6th 2007, CEA-LETI Grenoble.

[S21] "The future of Embedded Test within the Design for Micro & Nano manufacture NoE" (in collaboration with Prof A. Richardson[1], University of Lancaster), Workshop on Design for Reliability and Manufacturability in MNT, 24 April 2007, Stresa, Italy.

[S22] "Challenges in MEMS Manufacture Testing and embedded test solutions", NTC (Northern Test Center) Remote and Embedded Testing Seminar, Pohto, Oulu, Finlande, May 29th, 2007.

[S23] "Motionless testing of embedded inertial sensors", Design, Test & manufacturing Technologies for Integrated Micro&Nano systems Summit, Lancaster, October 1st-4th, 2007.

[S24] "Mécanismes non linéaires dans les dispositifs MEMS pour la récupération d'énergie", Journées Nationales du GDR Micro- et Nano-Systèmes, Besançon, 19 novembre 2009.

[S25] "Design and Test of Integrated-MEMS & CMOS-MEMS", Colloque "Frontier of Engineering France – Japon", Grenoble, 12 et 13 octobre 2010.

8. Synthèse

	89/07	2008	2009	2010	2011	
Revues Scientifiques avec Comité de Lecture (§ 1)	29	3	5	3	3	43
Conférences Internationales avec Actes et Comité de Lecture (§ 2)	74	11	11	9	9	114
Colloques sans actes ou à audience restreinte (§ 3 et 4)	56	4	2	0	1	63
Divers (Séminaires invités, brevets, rapports de contrat, § 5, 6 et 7)	44	0	2	1	0	47
Total	203	18	20	13	13	**267**

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